



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re application of: Van Schravendijk, *et al.*Attorney Docket No.:
NOVLP037C1/NVLS-000519C1

Application No.: 10/773,821

Examiner: DOLAN, JENNIFER M

Filed: February 5, 2004

Group: 2813

Title: APPLICATIONS AND METHODS OF
MAKING NITROGEN-FREE ANTI-
REFLECTIVE LAYERS FOR
SEMICONDUCTOR PROCESSING

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on October 14, 2005 in an envelope addressed to the Commissioner for Patents, Mail Stop RCE, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: _____

Tara Hayden

RESPONSE B

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is submitted in response to the Final Office Action mailed on June 14, 2005 and accompanies a Request for Continued Examination.

Amendments to the Claims are reflected in Listing of Claims, beginning on page 2 of this paper.

Remarks and arguments are in Remarks, beginning on page 5 of this paper.

10/20/2005 HDESTA1 00000034 10773821

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